Operating Procedure for EVAP2  
(Lesker PVD75 Ebeam/Thermal Evaporator)

Sample Load/Chamber Pump and Vent
1. To vent chamber and load sample, select the Start PC Vent icon.
2. Upon completion of vent cycle, open door and load sample.
3. Verify that Mylar window cover is in place, and replace if needed.
4. To pump chamber select the Start PC Pump icon.

Recipe Selection and Edit
1. Select the SQS-242 icon using the touch screen, or the track ball on the keyboard.
2. Select File.
4. Select the desired process. (EB Au, Therm Au Ge, etc…)
5. Select Yes.
6. NOTE:
   - Processes with the prefix EB utilize Electron Beam Source #1.
   - Processes with the prefix Thermal utilize Thermal Source #2.
7. Select Edit.
9. To edit the Deposition Rate, enter the desired rate in the SetPt window.
10. NOTE: SetPt values may range from .5A/sec to 5A/sec for all metals EXCEPT for Ni. Ni may be run at a maximum rate of 2A/sec.
11. To edit the Film Thickness, enter the desired thickness value in the FinalThick window.
12. NOTE: This value is expressed in KiloAngstroms
13. Select the SQS-242 icon to minimize that screen.

Run Process
14. Select the Deposition icon.
15. If you are using Electron Beam Source #1, select the desired Crucible Position for your process. Below are the allowable configurations for metals:

<table>
<thead>
<tr>
<th>Crucible Position</th>
<th>Metal Description</th>
</tr>
</thead>
<tbody>
<tr>
<td>Pos 1: Ti</td>
<td>(Directly In Hearth)</td>
</tr>
<tr>
<td>Pos 1: Cr</td>
<td>(Copper Crucible)</td>
</tr>
<tr>
<td>Pos 2: Al</td>
<td>(Directly In Hearth)</td>
</tr>
<tr>
<td>Pos 3: Pt</td>
<td>(Directly In Hearth)</td>
</tr>
<tr>
<td>Pos 4: Gold (Au)</td>
<td>(Tungsten Crucible with Spacers)</td>
</tr>
<tr>
<td>Pos 4: Silver (Ag)</td>
<td>(Tungsten Crucible)</td>
</tr>
</tbody>
</table>

*DO NOT CHANGE THE POSITION OF ANY METAL WITHOUT SMIF APPROVAL. ALL METALS MUST REMAIN IN THE ABOVE POSITIONS. CONTACT SMIF STAFF FOR INFO CONCERNING ALL OTHER METALS*
16. If you are using the Thermal Source #2 there is no Crucible Position selection.
17. In the **Power Window** verify that the EBeam and Thermal Source Power supply **Setpoints** are set to **0%**.
   - EB **ON** and EB **Off** icons control **Source #1** (EBeam Gun).
   - **Power Supply 2 On/Off** icon controls **Source #2** (Thermal Source).
18. Select the desired Power Supply **ON** icon.  (**EBeam or Thermal Source**)
19. Select the **Platen Motion** icon.
20. In the **Platen Motor** window select the Motor **ON** icon.
21. In the **Drive Motor Continuous** window select the **Fwd** icon to turn it **ON**.
22. Select the **Sigma** icon.
23. In the **SQS-242** window, verify the **Sigma Launch 242** is **ON**. If not, select **ON**.
24. In the the **Sigma Process Name** window verify that the desired recipe name is displayed.
25. In the **Sigma Control** window, select **Sigma Start Process ON**.
26. **This will START your process!**
27. Select **SQS-242** to view **Power Ramp** and **Dep Rate** graph if desired.
28. Select **View**.
29. Select **Sensor Reading** to display crystal info.

**Sample Unload**

30. Upon completion of your process, under the **Sigma Control** window select Sigma **Start Process OFF**.
31. Select the **Deposition** icon.
32. In the **Power** window turn the chosen power supply **OFF**.  (**See Step 17**).
33. Select **Start PC Vent**.  (Vent Time is approximately 5 minutes).
34. Open door and remove samples.
35. Close chamber door.
36. Select **Start PC Pump**

**How To Reboot the Computer After An Unrecoverable Error**

37. Shut down the computer using the Start menu.
38. Allow the system to sit idle for 10 seconds.
39. Restart the computer using the toggle switch located on the front panel.
40. Select the **KWare** icon.  Wait 10 seconds after software is fully open.
41. Login using “admin” as the user name and the password.  Wait 10 seconds.
42. Select the **Sigma Screen**.
43. Select the “**Launch SQS242**” icon.  There is no username or password required.
44. Wait 10 seconds.  System is ready for use.